





COLDBEAMS2012
 Wednesday October 3
 11:50 to 12:10 am 20 min





**CENTRE FOR QUANTUM COMPUTATION
& COMMUNICATION TECHNOLOGY**
 AUSTRALIAN RESEARCH COUNCIL CENTRE OF EXCELLENCE

Bypassing Liouville

Deterministic *single-ion-implanted* devices for reading atom quantum states

David N. Jamieson
 ARC Centre for Quantum Computation and Communication Technology
 School of Physics, University of Melbourne

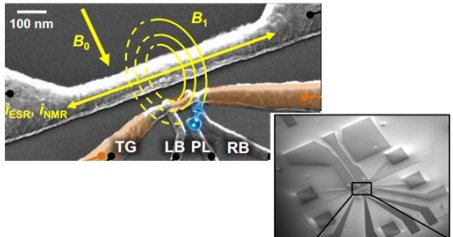


Melbourne Royal Exhibition Buildings UNESCO world heritage site

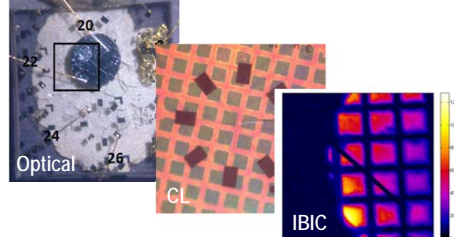
Wikipedia

1

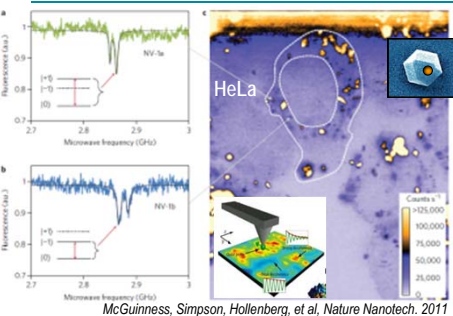
The Melbourne major projects



Quantum devices in Si:P

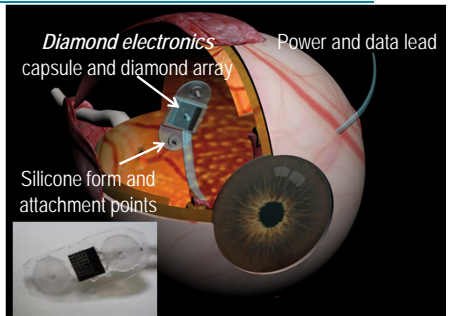


Diamond radiation dosimeter



N-V Nanodiamond decoherence probes

McGuinness, Simpson, Hollenberg, et al, Nature Nanotech. 2011



Bionic Eye

2



Part 1: Ion Beams In Melbourne

MeV ions, keV ions

3

30 kV FIB

- Beams of Ga, Si, Au, Ni
- 20 nm spot size
- Ion Beam Machining**

14 kV Colutron

- Beams of P, N, Te, As
- 200 micron spot size
- Up to 25 nm depth
- Single ion implants**

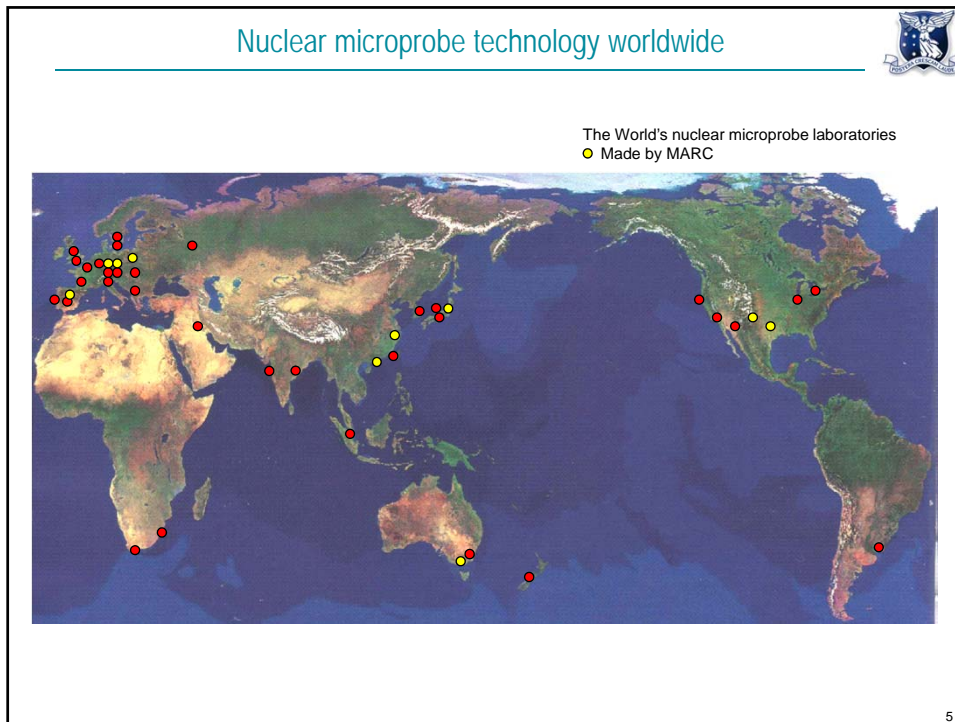
5U Pelletron accelerator

5 MV Nuclear Microprobe


- Micon beams of light ions
- Up to 100 micron depth**
- Single ion sensitivity


"Big fluffy source(s) of ions"
J. McClelland, COLDBEAMS 2012

Physical location: in basement under Rob Scholten's lab



Joseph Liouville (1809 – 1882)





Liouville's theorem (Hamiltonian): "the phase-space distribution function is constant along the trajectories of the system – that is that the density of system points in the vicinity of a given system point travelling through phase-space is constant with time."


http://en.wikipedia.org/wiki/Joseph_Liouville
 Born: 24 March 1809 (Ste Omer),
 Died: 8 September 1882 (Paris)

$$x\theta\sqrt{E} = const$$

The Castellarius


Purity Current Brightness	High fidelity transport Minimal leaks or aberrations Technological elegance	Precise delivery Amount on demand High reliability
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La fontaine d'Eure à Uzès




http://www.hydrad.com/

Pont du Gard



author

Castellum Divisorium



tripwaw.tripadvisor.com

6

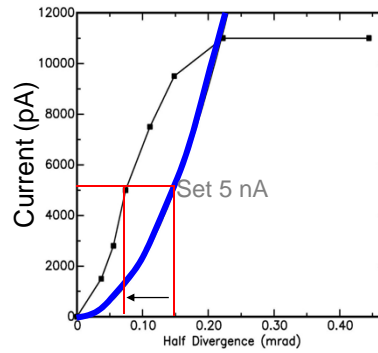
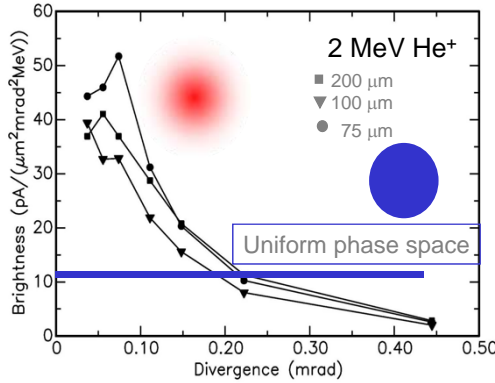
Ion Source Brightness: Flux Peaking



- Legge et al (1993) showed a **1 order of magnitude** decrease in probe size required a **5 orders of magnitude** increase in brightness for uniform model
- True situation more complicated: **1 order of magnitude** decrease in probe size requires **2 orders of magnitude** increase in brightness

For 5 nA divergence is 2.5 times less than uniform model so spherical aberration is reduced by a factor of 16

RF ion source on 5U Pelletron accelerator



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Quest for brighter sources



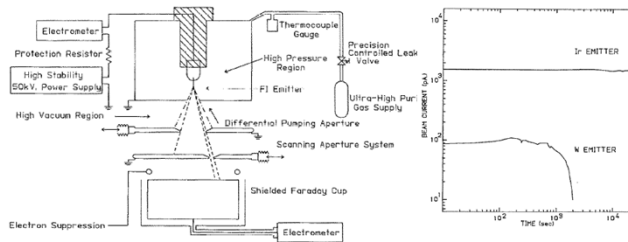
122 Nuclear Instruments and Methods in Physics Research B34 (1988) 122-126 North-Holland, Amsterdam

CHARACTERISTICS OF A HYDROGEN GAS FIELD ION SOURCE FOR MICROPROBE APPLICATION

G.L. ALLAN and G.J.F. LEGGE
Micro-Analytical Research Centre, School of Physics, The University of Melbourne, Parkville, Victoria, 3052, Australia

J. ZHU
Shanghai Institute of Nuclear Research, Shanghai, P.R. China

Did not work – significant technical difficulties fitting into the terminal of a high energy particle accelerator



10⁵ times brighter than RF source, but at cost of very large divergence

An analysis of the optics of a field ionization ion source for application with a scanning proton microprobe

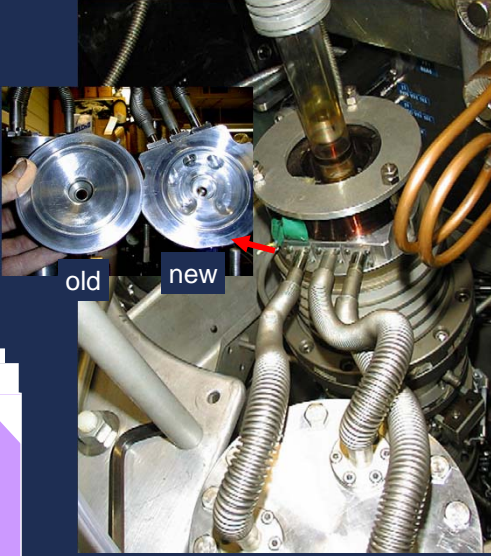
R. A. Colman, G. L. Allan, and G. J. F. Legge

Citation: *Rev. Sci. Instrum.* **63**, 5653 (1992); doi: 10.1063/1.1143396

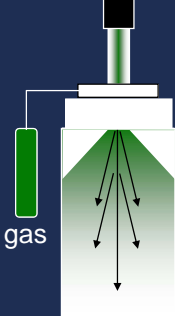
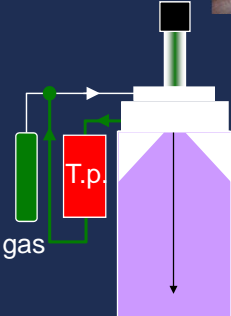
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Modify RF Ion Source

- Beam from ion source emerges with low energy
- Gas leakage from ion source canal fills low energy end of accelerator
- Gas scattering degrades ion source brightness
- Solution: Add *recirculating* turbopump



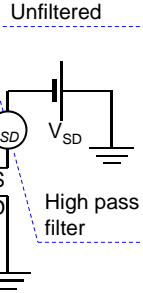
old new

From the work of Roland Szymanski

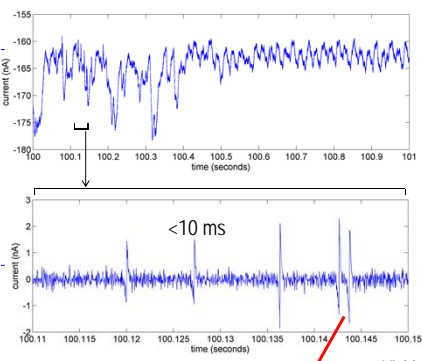
Mapping single ion impacts from delta- I_{SD}

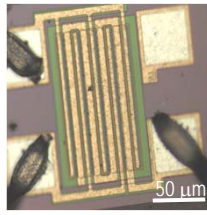
- 2 MeV He microbeam
- $\Delta V_G = 3.2$ microVolt/ion



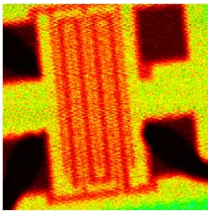
Unfiltered

High pass filter

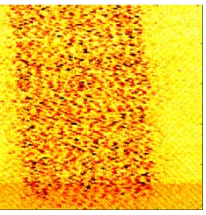




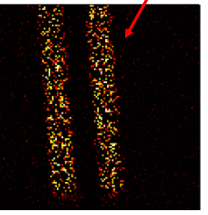
Optical



PIXE Si K_α



I_{SD} slow



I_{SD} fast

Yield

2.2 High

2

1.8

1.6

1.4

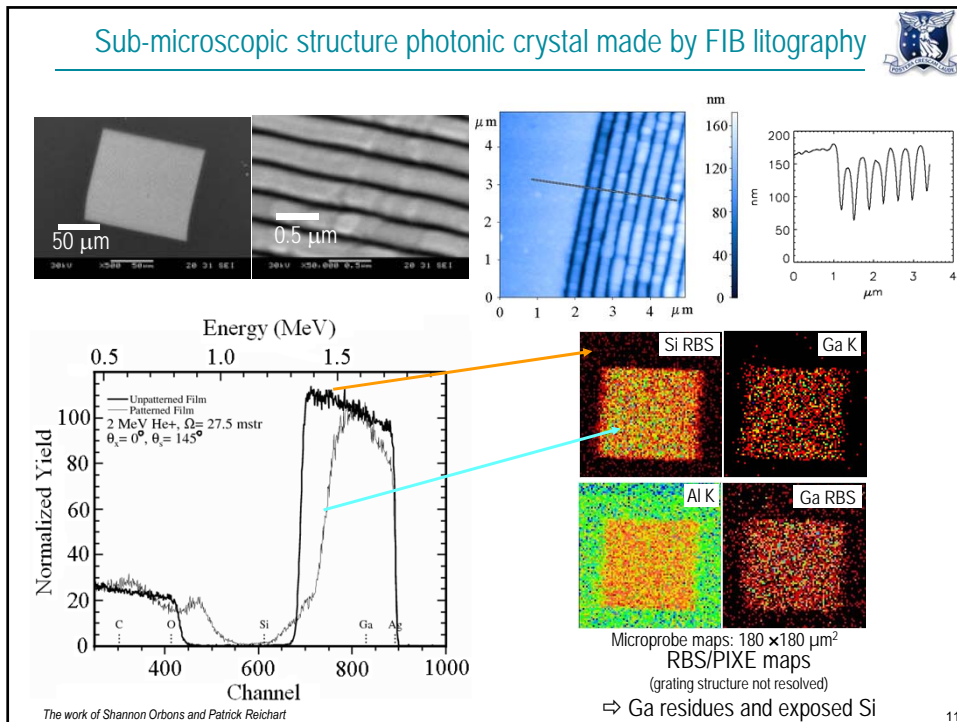
1.2

1

0.8

0.6 Low

Changyi Yang, Andrew Alves, et al. NIMB 2011 10



The quantum internet

H. J. Kimble

Quantum networks provide opportunities and challenges, frontiers including quantum computation, communication networks composed of many nodes and channels requires characterizing quantum coherence and entanglement. For interconnects, which convert quantum states from one photon to another, allowing the distribution of entangled quantum states between nodes.

Power Hackers: The U.S. Smart Grid Is Shaping Up to Be Dangerously Insecure

As smart grids become more efficient and control requires looking almost every aspect of the electricity grid up to the Internet, making it more vulnerable to cyber attacks.

Part 2: Deterministic Doping – Towards the quantum computer

“More than Moore”

Average number of dopants

Technology node (nm)

International Technology Roadmap for Semiconductors
2011 Edition
Emerging Research Materials
Section 6: Single ion implantation

Isotope Considerations



- Isotopic abundances and nuclear spin of semiconductors and donors:

^{28}Si	92.2%	0^+
^{29}Si	4.7%	$\frac{1}{2}^+$
^{30}Si	3.08%	0^+
^{31}P	100%	$\frac{1}{2}^+$
^{75}As	100%	$3/2^-$
^{121}Sb	57%	$5/2^-$
^{123}Sb	43%	$7/2^-$
^{209}Bi	100%	$9/2^-$

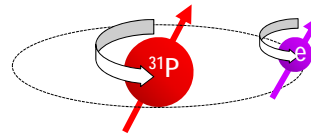
- Others:

^{69}Ga	60.1%	$3/2^-$
^{71}Ga	39.9%	$3/2^-$
^{12}C	98.3%	0^+
^{13}C	1.1%	$\frac{1}{2}^-$
^{14}C	$1e-10\%$	0^+
^{14}N	99.6%	1^+
^{15}N	0.36%	$\frac{1}{2}^-$
^{10}B	19.9%	3^+
^{11}B	80.1%	$3/2^-$



The standard ^{28}Si kilogram
Spherical to 0.6 nm

<http://www.acpo.csiro.au/avogadro.htm>



Approaches to "More than Moore"

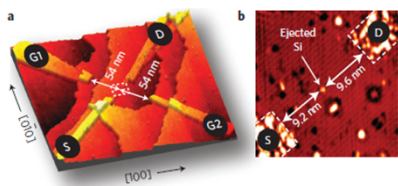


LETTERS
PUBLISHED ONLINE 19 FEBRUARY 2012 | DOI:10.1038/NANO.2012.21

nature nanotechnology

A single-atom transistor

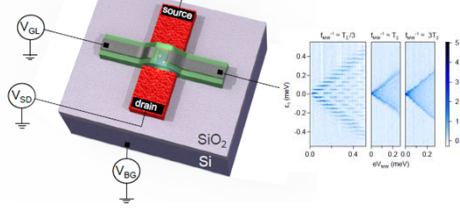
Martin Fuechsle¹, Jill A. Miwa¹, Suddhasatta Mahapatra¹, Hoon Ryu², Sunhee Lee¹, Oliver Warschkow⁴, Lloyd C. L. Hollenberg³, Gerhard Klimeck³ and Michelle Y. Simmons^{1*}



Coupling and coherent electrical control of two dopants in a silicon nanowire

E. Dupont-Ferrier¹, B. Roche¹, B. Voisin¹, X. Jehl¹, R. Wacziarg², M. Vizar², M. Sanoque¹ and S. De Franceschi¹

¹SF3MS, UMR-E CEA / UJF-Grenoble 1, INAC, Grenoble, F-38054, France
²CEA/LETI-MINATEC, CEA-Grenoble

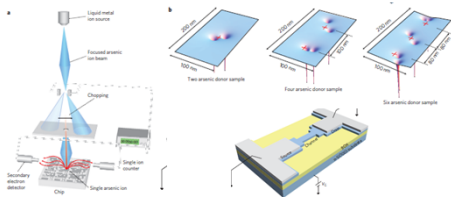


nature nanotechnology
PUBLISHED ONLINE 1 MAY 2012 | DOI:10.1038/NANO.2012.84

LETTERS

Anderson–Mott transition in arrays of a few dopant atoms in a silicon transistor

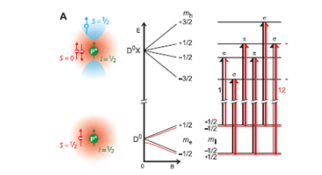
Enrico Prati^{1*}, Masahiro Hori¹, Filippo Guagliardo¹, Giorgio Ferrari¹ and Takahiro Shinada^{1*}



REPORTS
8 JUNE 2012 VOL 336 SCIENCE

Quantum Information Storage for over 180 s Using Donor Spins in a ^{28}Si "Semiconductor Vacuum"

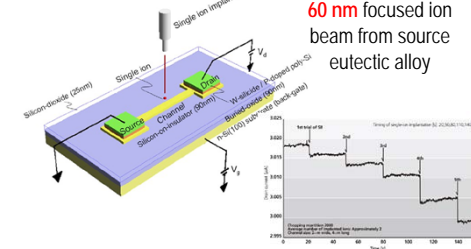
M. Steger¹, K. Sarotti², M. L. W. Thewalt^{2*}, J. J. L. Morton², H. Riemann², N. V. Abramoimov², P. Becker³, H.-J. Pohl¹



Deterministic Implantation Doping History

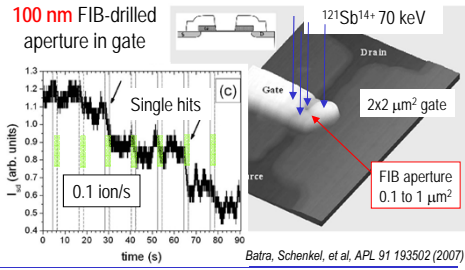


Waseda: Secondary electrons



Shinada, Ohdomari, et al., Nanotechnology 19 345202 (2008)

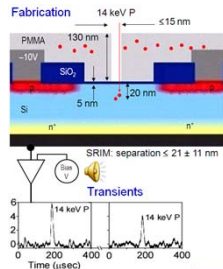
Berkeley: I_{SD} in MOSFET



Batra, Schenkel, et al., APL 91 193502 (2007)

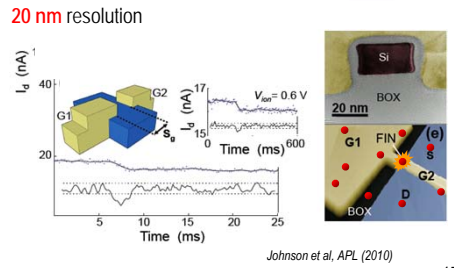
Ion Beam Induced Charge

15 nm EBL PMMA mask, active substrate detects single ion impact from induced charge transient



Jamieson, et al., APL (2005)

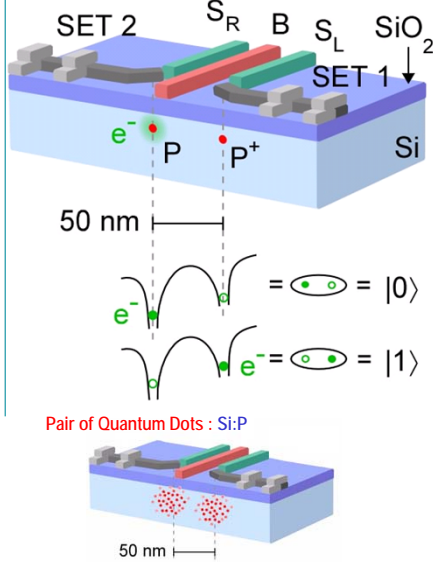
Self-aligned I_{SD} in MOSFET



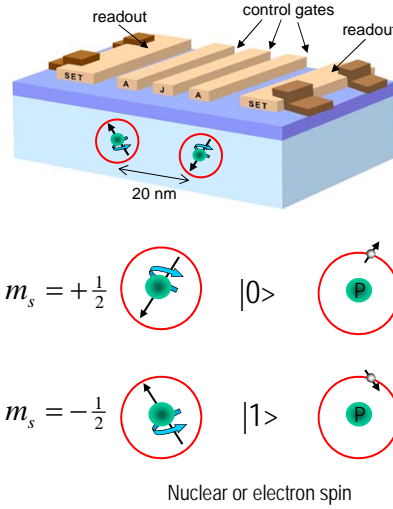
^{28}Si ($s=0$) ^{31}P ($s=1/2$) Qubits



Charge



Spin



Kane, Nature 1998

^{28}Si ($s=0$) ^{31}P ($s=1/2$) Qubits

Charge

SET 2

Single electron device: Can we **fabricate** to better than 50 nm? ✓

Single electron position: Can we **measure** to better than 50 nm? ✓

Single electron position: Can we **control** to better than 50 nm? ✓

Pair of Quantum Dots - Si:P

Does this work with counted atoms? ✓

Scale up beyond 2? (Red box)

Spin

Single spin device: Can we **fabricate** to better than 20 nm? ✓

Single spins: Can we **control**? ✓

Single nuclear spin: Can we **readout**? ✓

Single electron spin: Can we **readout**? ✓

readout

20 nm

$m = +\frac{1}{2}$

$|0\rangle$

$|1\rangle$

Kane, Nature 1998

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Addressing the challenge: Deterministic doping by IBIC

Electron beam lithography > IBIC > Anneal > Electron beam lithography > Measure

15 nm EBL PMMA mask, active substrate detects single ion impact from induced charge transient

14 keV P is maximum energy permissible owing to the constraint imposed by straggling


SRIM: separation $\leq 21 \pm 11$ nm

Transients

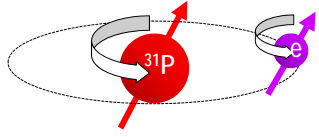
1,000 e-h pairs per single ion impact

Jamieson, et al., APL (2005)

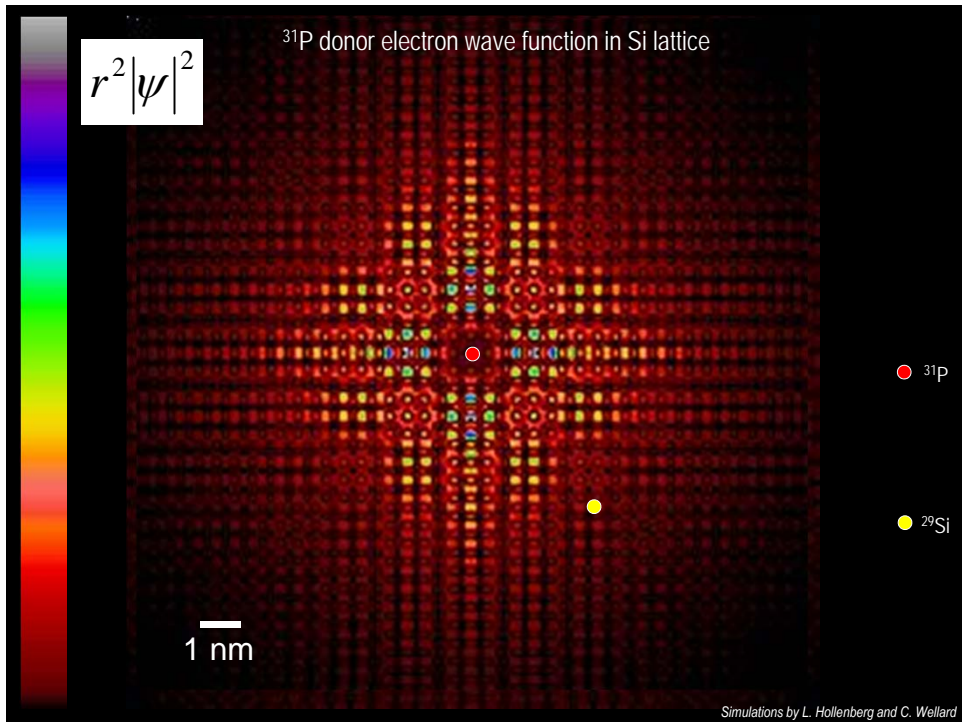
18

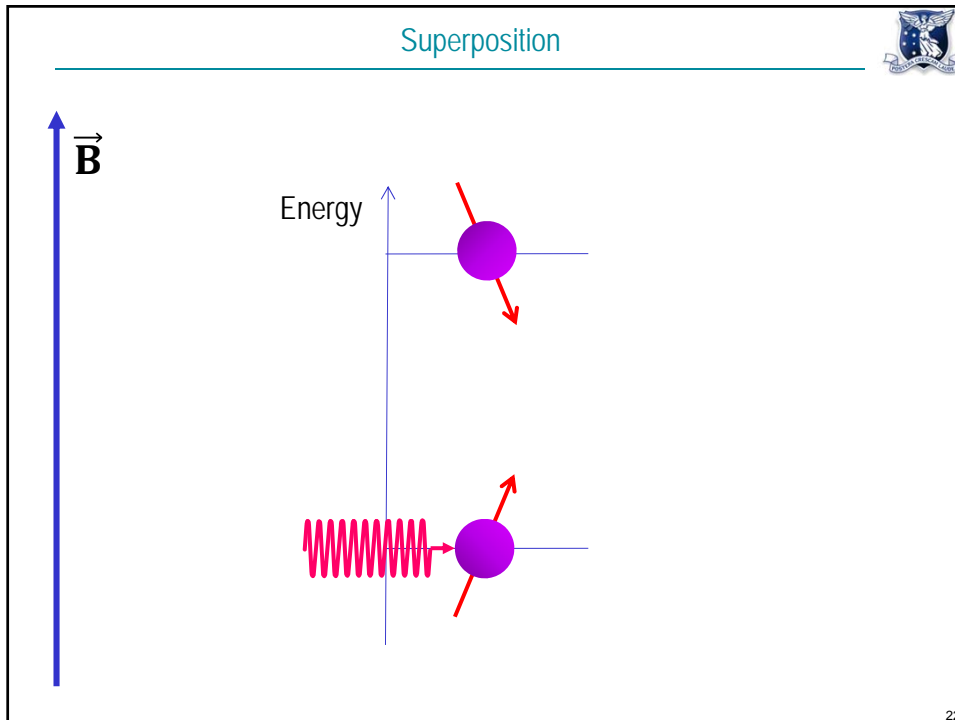
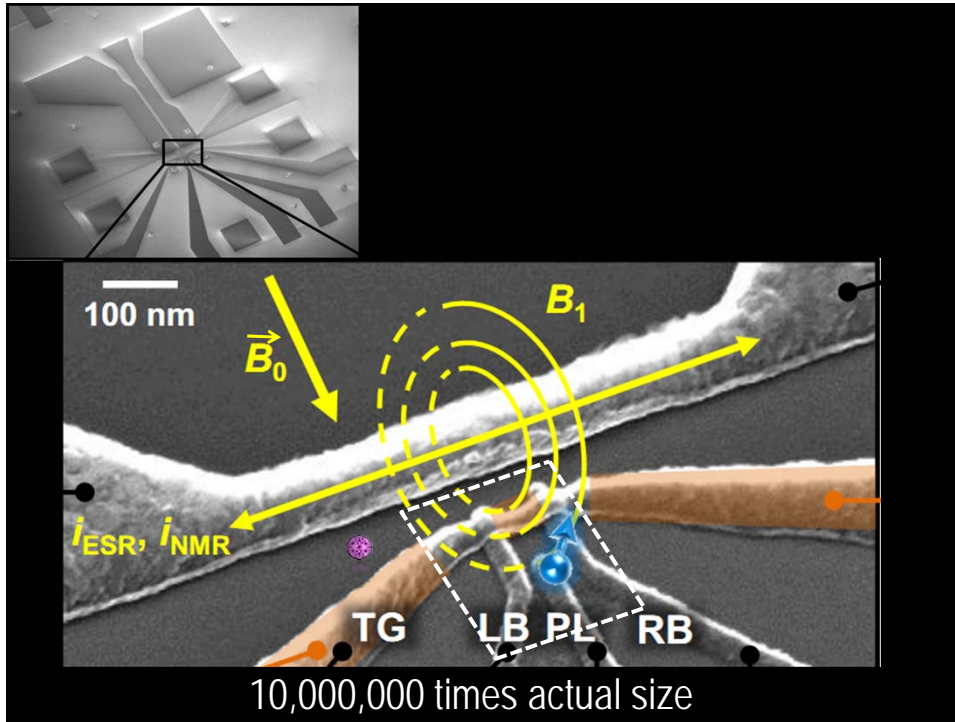


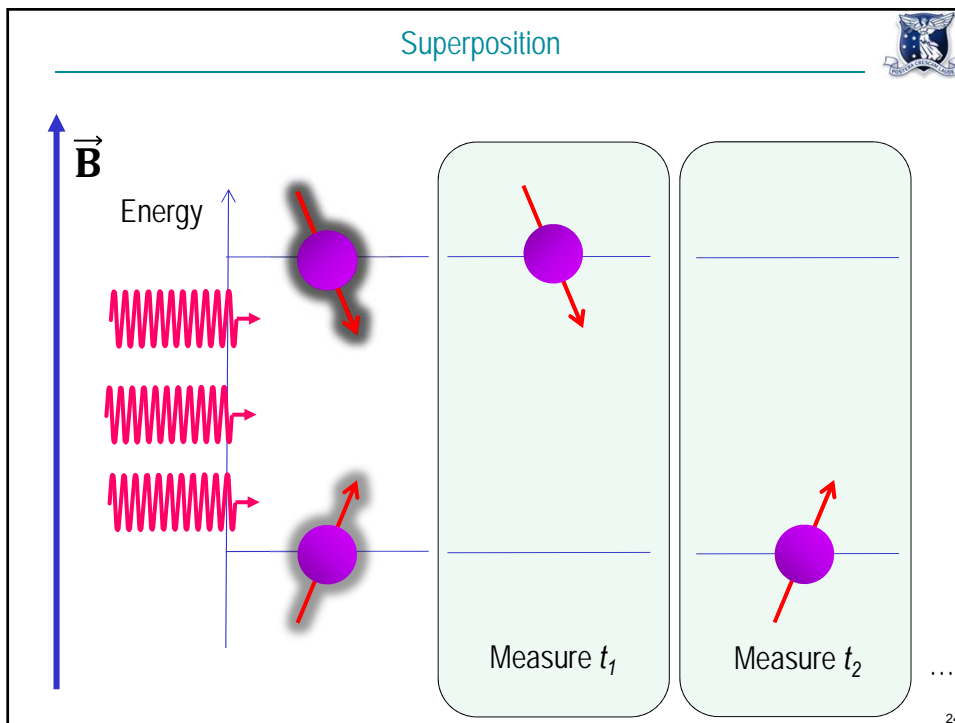
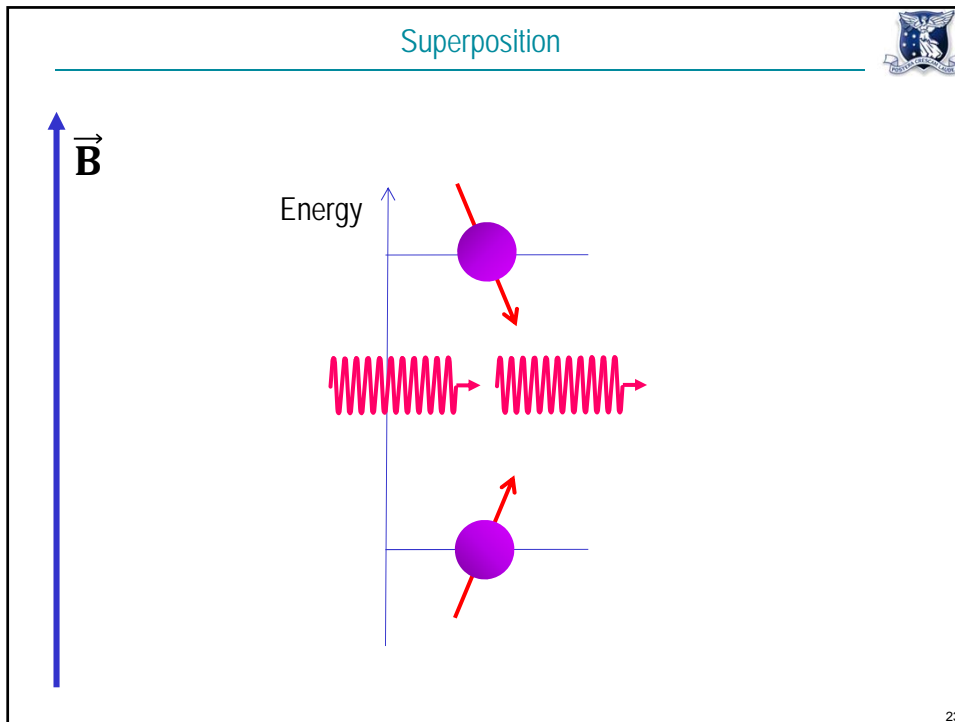
Part 3: Spin Qubit 101

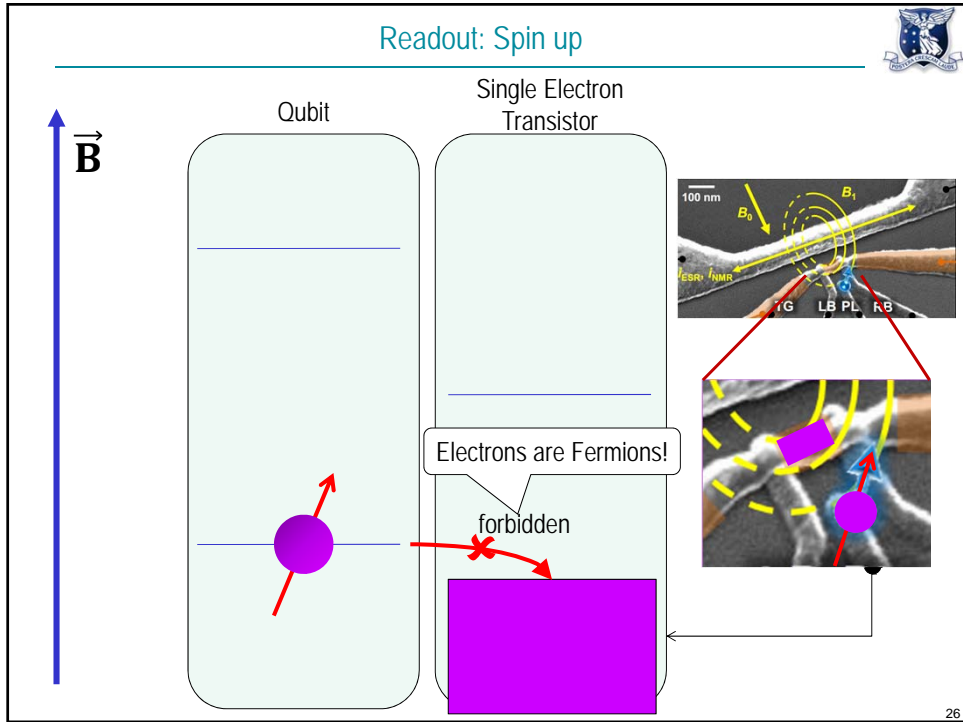
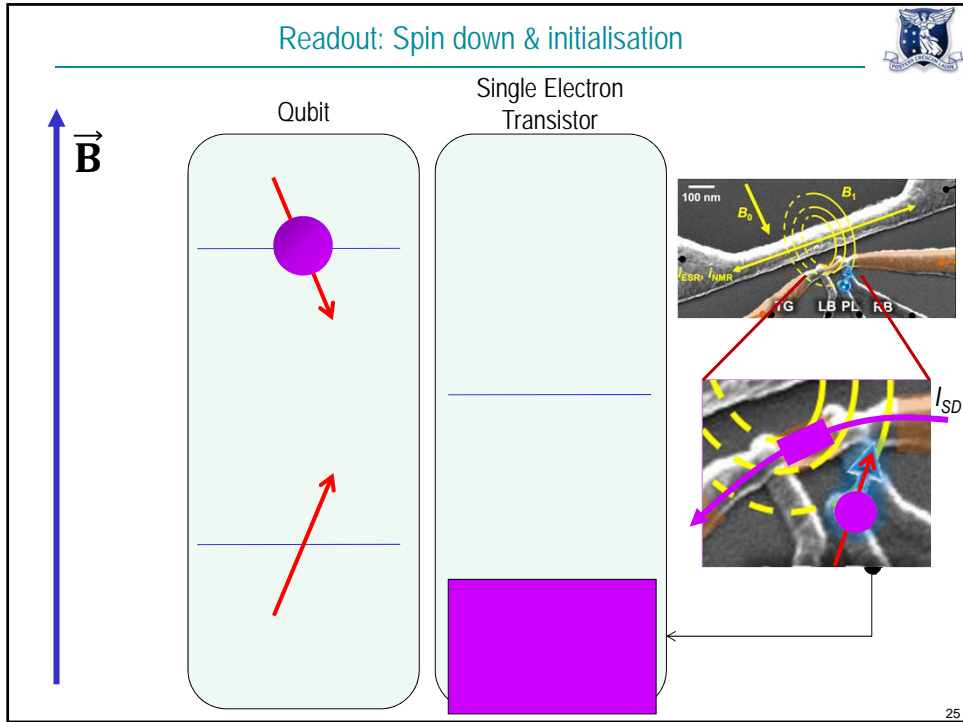


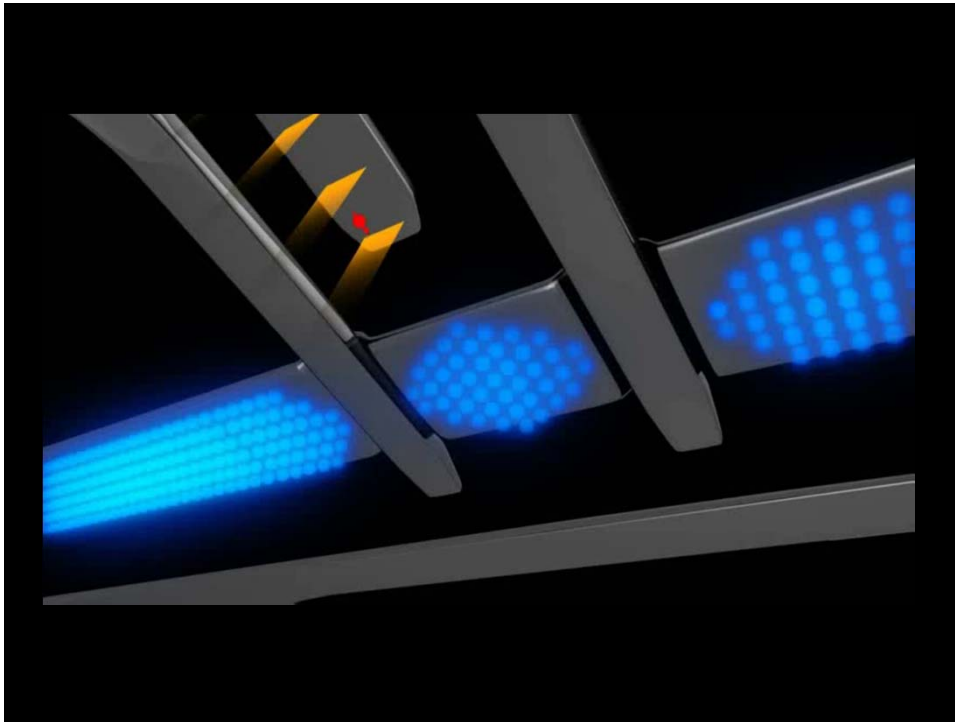
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LETTER Nature: Published online September 20 2012

doi:10.1038/nature11669

A single-atom electron spin qubit in silicon

Jerry J. Pla¹, Kuan Y. Tan¹, Juan P. Dehollain¹, Wee H. Lim¹, John J. L. Morton², David N. Jamieson³, Andrew S. Dzurak⁴ & Andrea Morello²

A single atom is the prototypical quantum system, and a natural candidate for a quantum bit, or qubit—the elementary unit of a quantum computer. Atoms have been successfully used to store and process quantum information in electromagnetic traps, as well as in diamond through the use of the nitrogen-vacancy-centre point defect¹. Solid-state electrical devices possess great potential to scale up such demonstrations from few-qubit control to large-scale quantum processors. Coherent control of spin qubits has been achieved in lithographically defined double quantum dots in both GaAs (ref. 3–5) and Si (ref. 6). However, it is a formidable challenge to combine the electrical measurement capabilities of engineered nanostructures with the benefits inherent in atomic spin qubits. Here we demonstrate the coherent manipulation of

serving as both a sensitive charge detector and an electron reservoir for the donor. Using gates PE and TG (Fig. 1a) to tune the electrochemical potential of the donor electron spin states (μ_{\uparrow} and μ_{\downarrow} for states $|1\rangle$ and $|2\rangle$) and the Fermi level in the SET island (μ_{SET}), we can discriminate between a $|1\rangle$ or $|2\rangle$ electron as well as perform electrical initialization of the qubit, following the procedure introduced in ref. 8. Our experiments use a two-step cyclical sequence of the donor potential, alternating between a spin read-out/initialization phase and a coherent control phase (see Supplementary Video). The qubit is first initialized in the $|1\rangle$ state through spin-dependent loading by satisfying the condition $\mu_{\uparrow} < \mu_{\text{SET}} < \mu_{\downarrow}$ (Fig. 1b). After this, the system is brought into a regime where the spin is a stable qubit ($\mu_{\uparrow, \downarrow} < \mu_{\text{SET}}$) and manipulated with various microwave pulse schemes resonant with



Part 4: Results

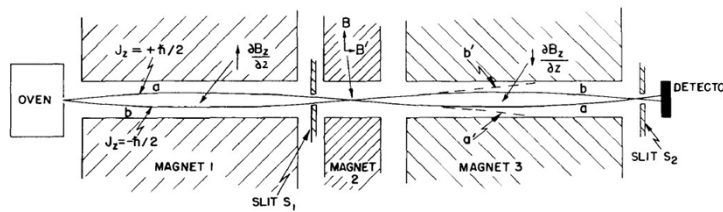
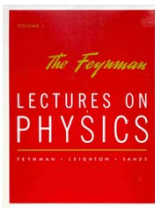


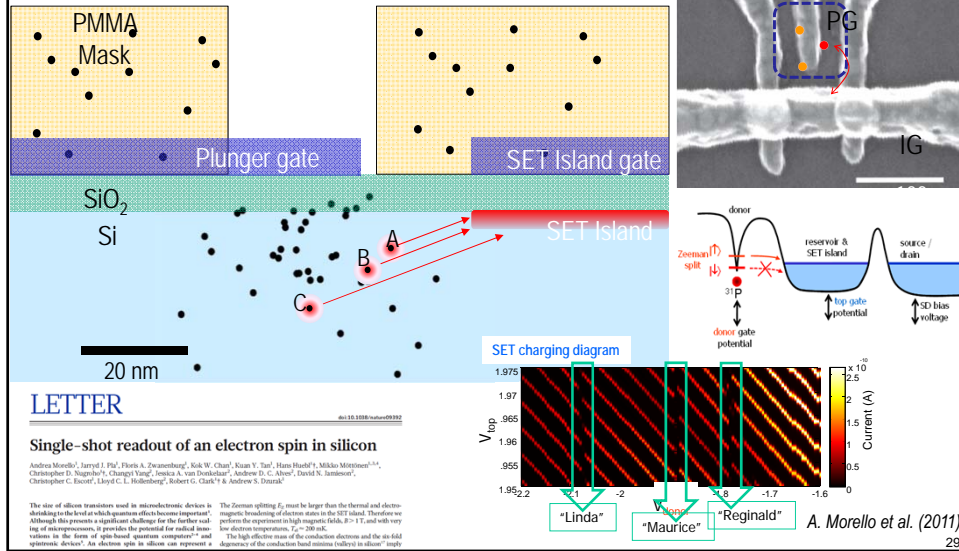
Fig. 35–5. The Rabi molecular-beam apparatus.

35–5

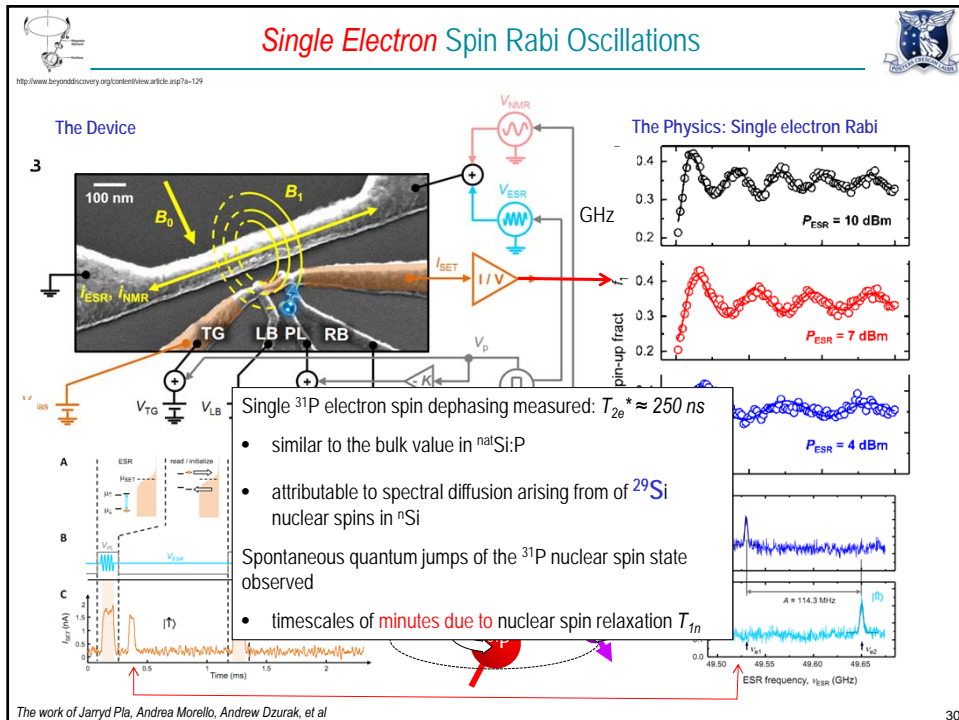
28

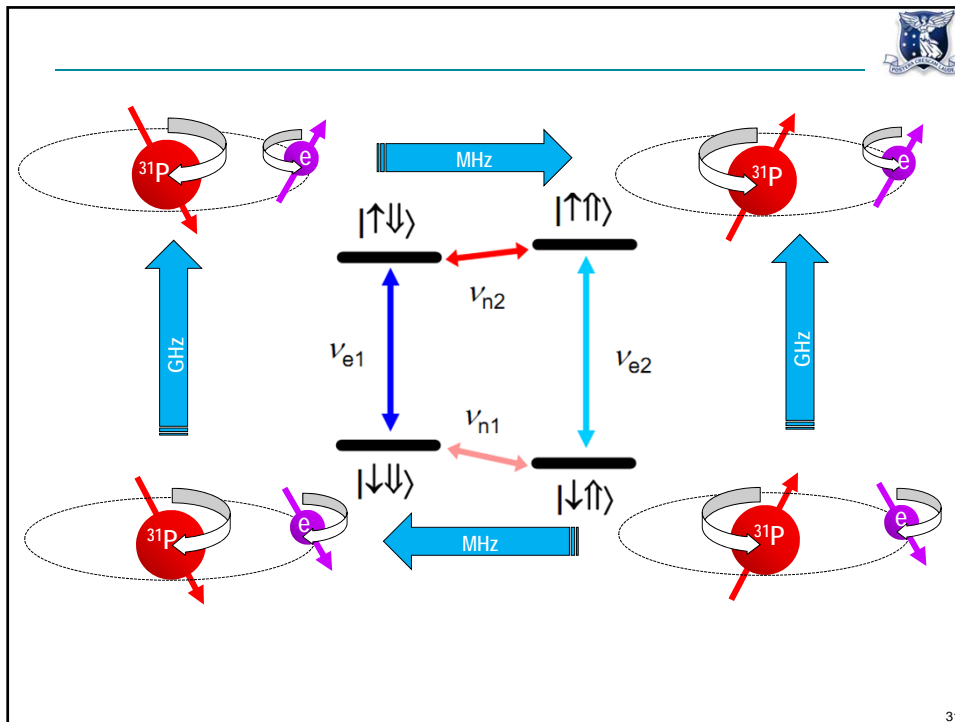
Post-implant donor selection: Nuclear and Electron spin readout

- 14 keV P⁺ Implant, 30 atoms into EBL mask + Spin dependent electron readout
- But nuclear spin is coupled to the electron spin via spin-orbit...

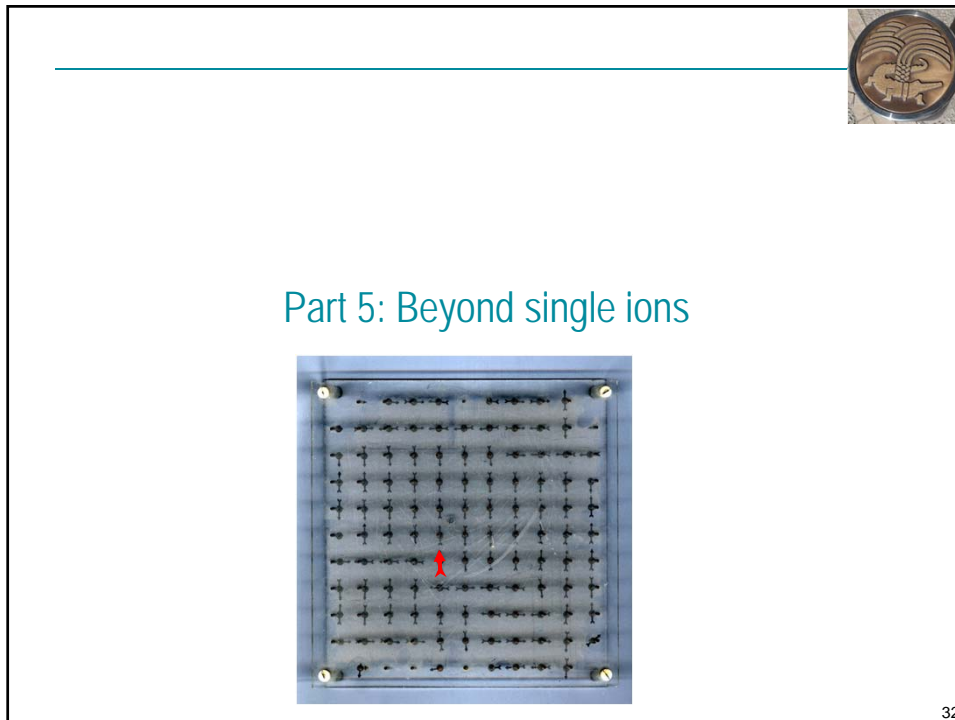


Single Electron Spin Rabi Oscillations





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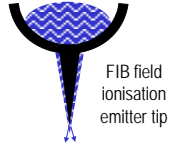


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³¹P ion beam for Melbourne FIB



Waseda P eutectic

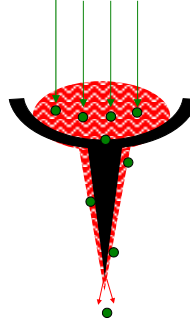


- P alloy: CuPtP
- Must use P⁺⁺ to avoid interference with P⁺ / Cu⁺⁺
- Not commercially available
- Japanese supplier no longer working on these materials

Dresden P eutectics

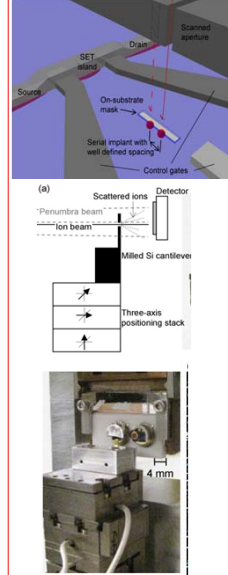
- NiP alloy:**
- Attacks Pt / W / Ir tips
 - Short lifetime
- Alternatives:**
- GaP – high melting point
 - InP – high melting point
- Exotics:**
- Pt-P-Sb (Hitachi)

UM P implant



- Use standard Ga source (off the shelf)
- Implant with 1x10¹⁷ P/cm² in Colutron
- Use ExB filter to select P ion beam
- Aim for 100 P/s

Nanostencil lithography

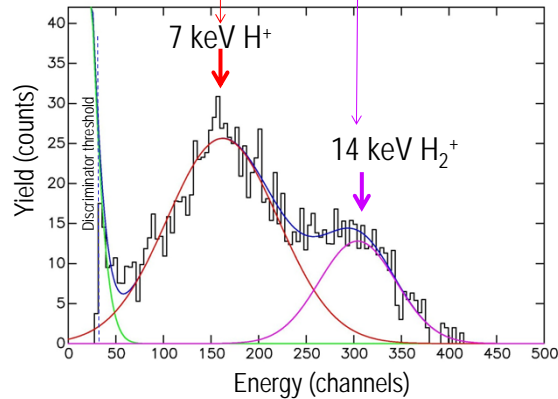
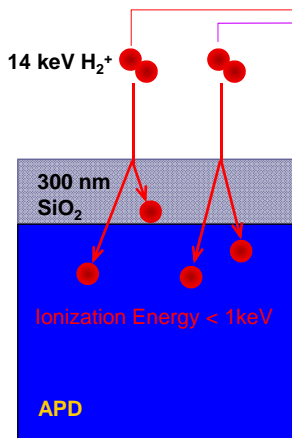


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Fast 2 atom prototype: P₂ molecular ions into APD

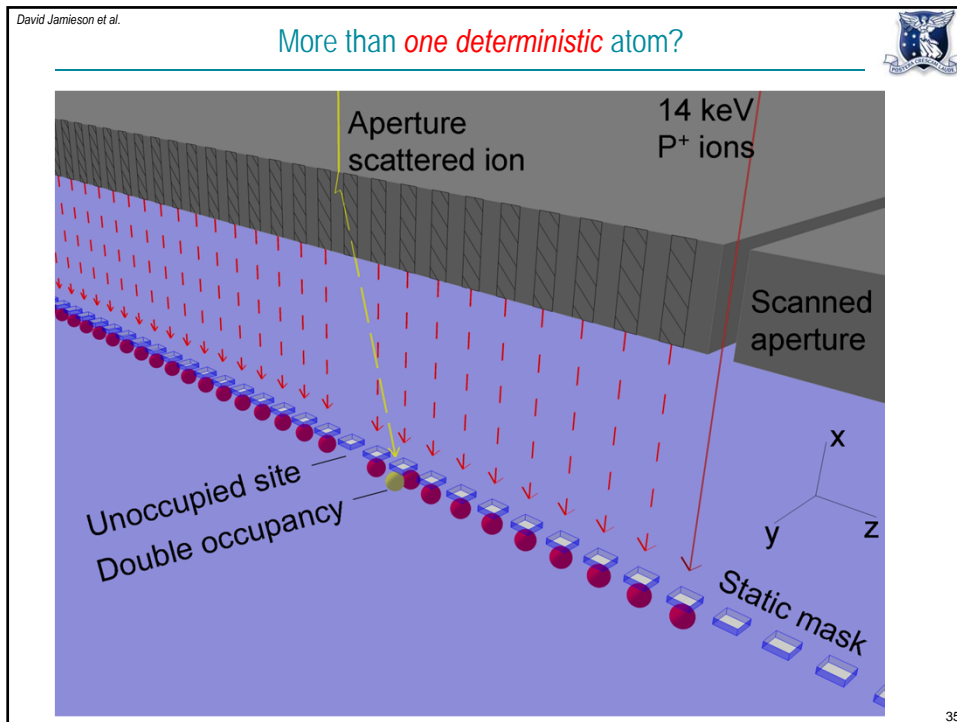


- Linear mode Hamamatsu APD
- Charge gain: ~ 100
- Detection limit: less than 1 keV ionization energy



<http://sales.hamamatsu.com/index.php?id=13166473>

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The reality: Scanned nanostencils

(a) Test photodiode
1000 mesh grid
Measurement photodiode
Milled Si cantilever
Ion beam
Three-axis positioning stack

(b) Si cantilever
Slots

(c) Pt
Si
250 nm

(d) 60 nm

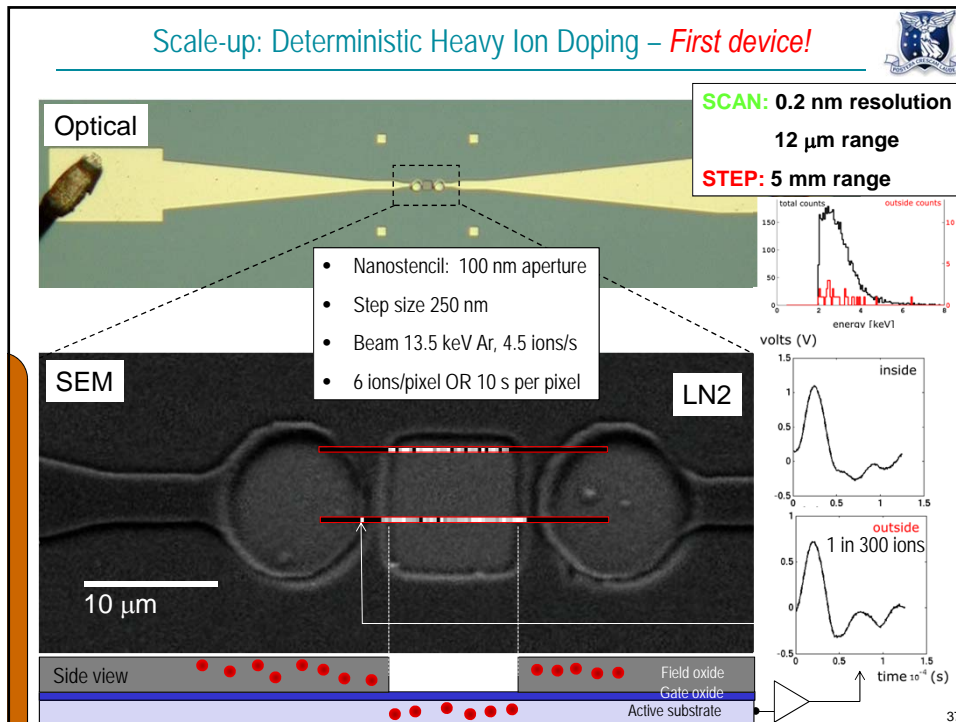
(e) 1 μm

(f) SiN₄ membrane
Before Pt
90 nm

(g) After Pt
30 nm

PhD thesis of Jessica van Donkelaar

6



Conclusions: What we want

All to be consistent with the device fabrication process flow!

*In order to have the best possible workshop, I would also stress that in complement to present your work the purpose of the conference is to give your **vision for the field**, your needs and **desires for future products** and applications, research, etc ...*
 Daniel Comparat, September 2012

Realistic:

- Sub-10 nm P⁺ ion beam; 100 ions/s; sub-10 nm positioning accuracy
 - For the production of large arrays of single donors in Si
- Ion Impact Detector Performance:
 - PIN: 1.5 keV noise threshold demonstrated (14 keV P), 0.5 keV in near future?
 - APD: 1000 gain demonstrated in commercial device
- Remaining issues
 - Gate oxide: have 5 to 8 nm, move to 2 nm desirable
 - Geiger mode/APD advanced development (7 keV P)

Dream:

- PH₄⁺ molecular ions
 - H bystander ions create greater ionisation leading to better deterministic doping signals
- PSi₄⁺ molecular ions
 - Even better: Si bystander ions amorphise surface layer and suppress channeling and allow shallow donors with less straggling – follows industry-standard B implant approach
- ²⁸Si island formation by ion deposition on ²⁸Si wafers

Si Quantum devices are REAL!
Long lived quantum spin states in Si demonstrated

Thank you Castellaria!

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